

Form PTO-1449 (Modified)		Atty Docket No. <i>JUN 01 2004</i> <i>C61</i>	P12759C	Serial No.: 10/618,226
List of Patents and Publications (Use several sheets if necessary)		Statement PATENT & TRADEMARK OFFICE		
		Applicant: Robert Chau et al.		
		Filing Date: July 11, 2003		

REFERENCE DESIGNATION		U.S. PATENT DOCUMENTS			
Examiner Initials	Document No.		Class	Sub-Class	Filing date if appropriate
	AA 6,020,024	Maiti et al.	427	248.1	
	AB 6,235,594 B1	Merchant et al.	438	287	
	AC 6,297,539 B1	Ma et al.	257	410	
	AD 6,365,467 B1	Joo	438	287	
	AE US2002/0102797A1	Muller et al.	438	287	
	AF US2002/0137317A1	Kaushik et al.	438	585	
	AG				
	AH				
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	AK				
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	AM				
	AN				
	AO				
	AP				

#### FOREIGN PATENT DOCUMENTS

No.	Document No.	Date	Country	Class	Sub-Class	Translation
	AQ EP1124262 A2	8/16/2001	European Patent Office	H01L	29/51	
	AR					
	AS					
	AT					
	AU					

#### OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

AV	Smith R.C. et al., "Chemical vapour deposition of the oxides of titanium, zirconium and hafnium for use as high-k materials in microelectronic devices. A carbon-free precursor for the synthesis of hafnium dioxide", Advanced Materials for Optics and Electronics, Vol. 10, 2000, pp. 105-114.
AW	
AX	
AY	
AZ	

Examiner *Burkhardt* Date Considered *11/28/04*

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.